CLAIMS

1. A method of producing a superconductor, comprising the step of forming a superconducting layer on a base layer by performing a film deposition at least two times, wherein the film thickness of a superconducting film made in each film deposition is $0.3~\mu m$ or less.

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- 2. A method of producing a superconductor according to claim 1, wherein the superconducting layer having a layer thickness in the range of 0.75 μm to 3 μm is formed on the base layer by performing the film deposition at least three times.
- 3. A method of producing a superconductor according to claim 1 or claim 2, wherein a supply area velocity of the base layer in each film deposition is at least $0.04~\text{m}^2/\text{h}$.
 - 4. A superconductor comprising a superconducting layer formed by performing film deposition on a base layer at least three times, wherein the superconducting layer has a layer thickness in the range of 0.75 μ m to 3.0 μ m, the film thickness of a superconducting film made in each film deposition being 0.3 μ m or less.